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CONFIRMATION NO. 3486

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| SERIAL NUMBER 10/506,636 | FILING OR 371(c) DATE 09/03/2004 RULE | CLASS 349 | GROUP ART UNIT 2871 | ATTORNEY DOCKET NO. 61982(70904) |
| APPLICANTS Naoto Yokoyama, Matsusaka-shi, JAPAN; Mitsuaki Morimoto, Matsusaka-shi, JAPAN; Makoto Nakahara, Nara-shi, JAPAN; Takao Murayama, Nagareyama-shi, JAPAN; Akira Hirai, Ushiku-shi, JAPAN; Satoshi Yawata, Kitakannbara-gun, JAPAN; | | | | |
| ** CONTINUING DATA ***** This application is a 371 of PCT/JP03/01674 02/17/2003 | | | | |
| ** FOREIGN APPLICATIONS ***** JAPAN 2002-59462 03/05/2002 JAPAN 2002-318911 10/31/2002 | | | | |
| Foreign Priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met Allowance Verified and Acknowledged _____ Examiner's Signature Initials | | STATE OR COUNTRY JAPAN | SHEETS DRAWING 20 | TOTAL CLAIMS 29 |
| | | | | INDEPENDENT CLAIMS 5 |
| ADDRESS 21874 | | | | |
| TITLE Method for holding substrate in vacuum, method for manufacturing liquid crystal display device, and device for holding substrate | | | | |
| FILING FEE RECEIVED 1580 | FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following: | | <input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit | |